

United States Patent and Trademark Office





UNITED STATES DEPARTMENT OF COMMERCE United States Patent and Trademark Office Address: COMMISSIONER OF PATENTS AND TRADEMARKS Washington, D.C. 20231 www.uspto.gov

APPLICATION NO.	FILING DATE	FIRST NAMED INVENTOR	ATTORNEY DOCKET NO.	CONFIRMATION NO.
09/292,132	04/14/1999	SALMAN AKRAM	MI22-1171	3104
21567	7590 10/02/2002			
WELLS ST. JOHN ROBERTS GREGORY & MATKIN P.S. 601 W. FIRST AVENUE SUITE 1300 SPOKANE, WA 99201-3828			EXAMINER	
			MULPURI, SAVITRI	
			ART UNIT	PAPER NUMBER
			2812	
			DATE MAILED: 10/02/2002	

Please find below and/or attached an Office communication concerning this application or proceeding.

Application No.

09/292,132

Applicant(s)

Examiner

Art Unit

Akram et al

L II Die in e	112 1 12 1 10 1 1	_
		۱۱
		IJ
		11
		I

Office Action Summary

		Savitri Mulpuri	2812			
	- The MAILING DATE of this communication appears	on the cover sheet with the corres	pondence address			
	or Reply		!			
THE N	ORTENED STATUTORY PERIOD FOR REPLY IS SET MAILING DATE OF THIS COMMUNICATION. ons of time may be evailable under the provisions of 37 CFR 1.136 (a). In date of this communication.					
If the pIf NO pFailureAny rep	eriod for reply specified above is less than thirty (30) days, a reply within the eriod for reply is specified above, the maximum statutory period will apply a to reply within the set or extended period for reply will, by statute, cause the ply received by the Office later than three months after the mailing date of a patent term adjustment. See 37 CFR 1.704(b).	and will expire SIX (6) MONTHS from the mailing the application to become ABANDONED (35 U.S.)	ng date of this communication. S.C. § 133).			
Status						
1) 💢	Responsive to communication(s) filed on Aug 14, 2	2002	<u> </u>			
2a) 🗌	This action is FINAL . 2b) 💢 This act	tion is non-final.				
3) 🗆	Since this application is in condition for allowance except for formal matters, prosecution as to the merits is closed in accordance with the practice under <i>Ex parte Quayle</i> , 1935 C.D. 11; 453 O.G. 213.					
Disposit	ion of Claims					
4) 💢	Claim(s) 51-53, 55-59, and 62-83	is/are	pending in the application.			
4	a) Of the above, claim(s)	is/ar	e withdrawn from consideration.			
5) 💢	Claim(s) <u>62-67 and 80</u>		is/are allowed.			
6) 💢	Claim(s) 51-53, 55-59, 68-79, and 81-83		is/are rejected.			
7) 🗆	Claim(s)		is/are objected to.			
8) 🗆	Claims	are subject to restric	ction and/or election requirement.			
Applica	tion Papers					
9) 🗆	The specification is objected to by the Examiner.		ļ			
10)□	The drawing(s) filed on is/are	e a) \square accepted or b) \square objecte	ed to by the Examiner.			
	Applicant may not request that any objection to the o					
11)□	The proposed drawing correction filed on	is: a) approved	b) \square disapproved by the Examiner.			
	If approved, corrected drawings are required in reply	to this Office action.				
12)	The oath or declaration is objected to by the Exam	iner.				
•	under 35 U.S.C. §§ 119 and 120					
	Acknowledgement is made of a claim for foreign p	riority under 35 U.S.C. § 119(a)	-(a) or (t).			
	I All b) ☐ Some* c) ☐ None of:	and the second second second				
	1. Certified copies of the priority documents have		la.			
	2. Certified copies of the priority documents have					
	3. Copies of the certified copies of the priority days application from the International Bure se the attached detailed Office action for a list of the	au (PCT Rule 17.2(a)).	this ivational Stage			
14)	Acknowledgement is made of a claim for domestic	·	(e).			
a) [
15)	Acknowledgement is made of a claim for domestic					
Attachm	ent(s)					
1) No	tice of References Cited (PTO-892)	4) Interview Summary (PTO-413) Paper				
	tice of Draftsperson's Patent Drawing Review (PTO-948)	5) Notice of Informal Patent Application	(PTO-152)			
3) [] Inf	ormation Disclosure Statement(s) (PTO-1449) Paper No(s).	6) Other:				

Application/Control Number: 09292132

Art Unit:

DETAILED ACTION

This action is in response to the applicant's arguments filed on 6/13/02.

Claim Rejections - 35 USC § 103

The following is a quotation of 35 U.S.C. 103(a) which forms the basis for all obviousness rejections set forth in this Office action:

(a) A patent may not be obtained though the invention is not identically disclosed or described as set forth in section 102 of this title, if the differences between the subject matter sought to be patented and the prior art are such that the subject matter as a whole would have been obvious at the time the invention was made to a person having ordinary skill in the art to which said subject matter pertains. Patentability shall not be negatived by the manner in which the invention was made.

Claims 51-53, 76-78, 82-83 are rejected under 35 U.S.C. 103(a) as being unpatentable over Suzuki et al or Oikawa (JP5-102067 from IDS) in combination with Pan '525

Suzuki et al and Oikawa discloses a method of making a device by the following process steps. Providing a substrate, forming gate oxide layer and then annealing in any halogen elemental such as chlorine(Suzuki) injection technique by Oikawa and forming polysilicon gate electrode.

Both Suzuki et al and Oikawa do not disclose concentration of fluorine. Oikawa even

Art Unit:

disclose insitu doping of chlorine in gate oxide (see page 5,lines 1-12) in translation document).

Pan'525 discloses diffusion of fluorine into gate oxide at the concentration of 5 X 10 ²⁰/cm ³ (see col. 5, lines 15-27). It would have been obvious to one of ordinary skill in the art to have concentration in the invention of Suzuki or Oikawa because such concentration only at edges of the gate oxide in Pan is suitable for hot electron carrier suppression.

Claims 55-59, 68-75, 79, 81 are rejected under 35 U.S.C. 103(a) as being unpatentable over Gardner et al in Pan '525

Gardener et al disclose a method of making a FET device by the following process steps:

Providing a gate oxide layer on as surface of a substrate; forming a gate electrode on gate oxide layer, wherein side walls of the gate oxide and gate electrode are aligned; forming side walls spacers on the aligned side walls of the gate oxide and gate electrode, wherein side walls having fluorine either by doping or ion implantation; heat-treating the substrate with spacer in nitrogen ambient to suppress hot carrier effect (see col. 3-col. 5). Claim 68 is limited to "forming spacers with chlorine or fluorine only on lateral edge of the gate and not how spacers or formed with respect to gate oxide

Application/Control Number: 09292132

Art Unit:

Gardener et al do not disclose (1) concentration of the fluorine in the range of 1 X 10 ¹⁹ to 1 X 10^{21} / cm ³ and concentration depth not more than 500 angstroms (3) forming gate oxide extending laterally past the lateral edges of the gate.

Pan '525 discloses diffusion of fluorine into gate oxide at the concentration of 5 X 10 $^{20}/\mathrm{cm}$ 3 (see col. 5, lines 15-27)

Claims 62-67, 80 are allowed because spacers containing fluorine are formed on gate oxide is not taught in the prior art.

Applicant's arguments with respect to claims 51-59, 62-83 have been considered but are moot in view of the new ground(s) of rejection.

Any inquiry concerning this communication or earlier communications from the examiner should be directed to S. Mulpuri whose telephone number is (703) 305-5184. The fax phone number for the organization where this application or proceeding is assigned is (703) 308-7722.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is (703) 308-0956.

SAVITRI MULPURI PRIMARY EXAMINER